

***Amendments to the Claims***

This listing of claims will replace all prior versions, and listings of claims in the application.

1. (Currently Amended) A pressure gauge, comprising:

a ~~diaphragm~~diaphragm having a rigid outer portion and a ~~displaceable~~displaceable semi-elastic inner portion that is sensitive to pressure changes in a range of approximately 0.1 to 0.5 inches of water, that the inner portion displaces in response to a pressure difference between first and second sides of the ~~diaphragm~~diaphragm;

a sensor located proximate to the ~~diaphragm~~diaphragm and adapted to sense the displacement of the ~~diaphragm~~diaphragm inner portion; and

a monitor and control system coupled to the sensor and adapted to determine the pressure difference from the displacement of the ~~diaphragm~~diaphragm.

2. (Cancelled)

3. (Currently Amended) The pressure gauge according to claim 1, further comprising an optically reflective coating on a first side of the ~~diaphragm~~diaphragm inner portion, wherein the sensor includes an optical transmitter and receiver optically aligned with the optically reflective coating.

4. (Original) The pressure gauge according to claim 3, wherein the sensor comprises an interferometer.

5. (Original) The pressure gauge according to claim 3, wherein the sensor comprises a white light interferometer.

6. (Currently Amended) The pressure gauge according to claim 3, wherein the sensor comprises:

a light transmitting module; and

a light sensing module adapted to directly receive a first light beam transmitted from the light transmitting module, and to receive a second light beam transmitted from the light transmitting module and reflected from the ~~diaphragm~~diaphragm;

wherein the monitor and control system calculates the displacement of the ~~diaphragm~~diaphragm from an interference pattern generated from the first and second lights.

7. (Currently Amended) The pressure gauge according to claim 6, wherein the light transmitting module comprises a transmitting fiber having an output coupled to a diffraction device that separates a source light into the first and second lights, wherein changes in the ~~diaphragm~~diaphragm displacement cause the interference pattern to include intensity modulated light, wherein the monitor and control system calculates the ~~diaphragm~~diaphragm displacement from the intensity modulated light.

8. (Currently Amended) The pressure gauge according to claim 6, wherein the light transmitting module comprises first and second transmitting fibers, the first transmitting fiber outputting the first light at a first wavelength, the second transmitting fiber outputting the second light at a second wavelength, wherein the second wavelength is phase shifted relative to the first wavelength, wherein changes in the ~~diaphragm~~diaphragm displacement cause the interference pattern to change with a substantially constant speed, wherein the monitor and control system comprises a counter that decodes the ~~diaphragm~~diaphragm displacement from the substantially constant speed.

9. (Currently Amended) The pressure gauge according to claim 1, wherein the inner portion of the ~~diaphragm~~diaphragm includes a grounded metallic surface, wherein the sensor includes a capacitive sensing device positioned adjacent to the grounded metallic surface, and wherein the monitor and control system determines the displacement based on capacitive changes in the capacitive sensing device.

10. (Currently Amended) A proximity sensor for lithography, comprising:  
a measurement leg having a measurement probe coupled thereto;  
a reference leg having a reference probe coupled thereto;  
a bridge portion coupled between the measurement leg and the reference leg; and  
a diaphragm pressure sensor disposed within the bridge portion.

11. (Currently Amended) The proximity sensor according to claim 10,  
wherein the pressure sensor comprises:

a diaphragm having a rigid outer portion and a ~~displaceable~~displaceable  
inner portion that displaces in response to a pressure difference between the  
measurement leg and the reference leg;

a sensor located proximate to the diaphragm and adapted to sense the  
displacement of the diaphragm inner portion; and

a monitor and control system coupled to the sensor and adapted to  
determine the displacement of the diaphragm and adapted to determine the pressure  
difference from the displacement.

12. (Currently Amended) A proximity sensor for lithography, comprising:

a measurement leg having a measurement probe coupled thereto;

a reference pressure;

a bridge portion coupled between the measurement leg and the reference  
pressure;

a diaphragm disposed within the bridge portion, the diaphragm including  
a rigid outer portion and a ~~displaceable~~displaceable inner portion that displaces in  
response to a pressure difference between the measurement leg and the reference  
pressure;

a sensor located proximate to the diaphragm and adapted to sense the  
displacement of the diaphragm inner portion; and

a monitor and control system coupled to the sensor and adapted to determine the displacement of the diaphragm and to determine the pressure difference from the displacement.

13. (Currently Amended) A lithography topography mapping device, comprising:

a measurement leg having a measurement probe coupled thereto;

a reference pressure;

a bridge portion coupled between the measurement leg and the reference pressure;

a diaphragm disposed within the bridge portion, the diaphragm including a rigid outer portion and a ~~displaceable~~displaceable inner portion that displaces in response to a pressure difference between the measurement leg and the reference pressure;

a sensor located proximate to the diaphragm and adapted to sense the displacement of the diaphragm inner portion; and

a monitor and control system coupled to the sensor and adapted to determine the displacement of the diaphragm and to determine the pressure difference from the displacement.

14. (New) The pressure gauge according to claim 1, wherein the semi-elastic inner portion comprises kapton.

15. (New) The pressure gauge according to claim 1, wherein the semi-elastic inner portion comprises mylar.

16. (New) The pressure gauge according to claim 1, wherein the semi-elastic inner portion comprises rubber.